



Středoevropský technologický institut  
BRNO | ČESKÁ REPUBLIKA

# Electron microscopy

InnoCore project

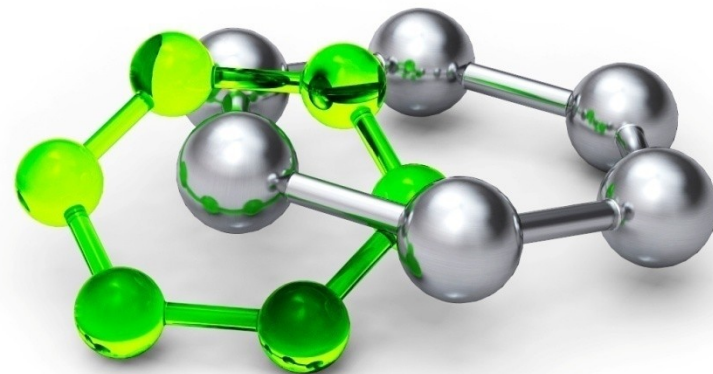
Jiri Novacek



EVROPSKÁ UNIE  
EVROPSKÝ FOND PRO REGIONÁLNÍ ROZVOJ  
INVESTICE DO VAŠÍ BUDOUCNOSTI



OP Výzkum a vývoj  
pro inovace



# Syllabus

- **Lecture 1: Applications of electron microscopy in life-science research**
- **Lecture 2: Transmission electron microscope, cryo-electron microscopy, principles of image formation**
- **Lecture 3: Data alignment in 2D, techniques for 3D model determination in cryo-EM**

# Syllabus

- Lecture 1: Applications of electron microscopy in life-science research
- **Lecture 2: Transmission electron microscope, cryo-electron microscopy, principles of image formation**
- Lecture 3: Data alignment in 2D, techniques for 3D model determination in cryo-EM

# Content

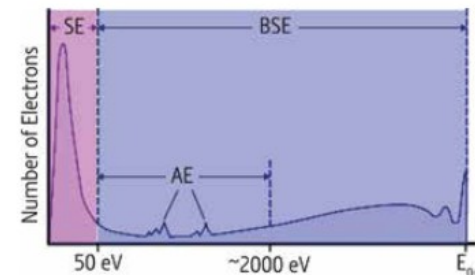
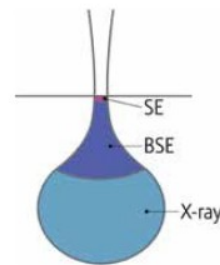
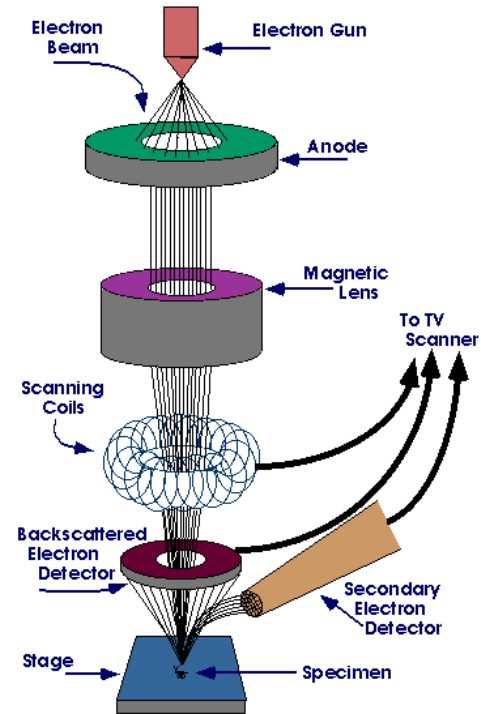
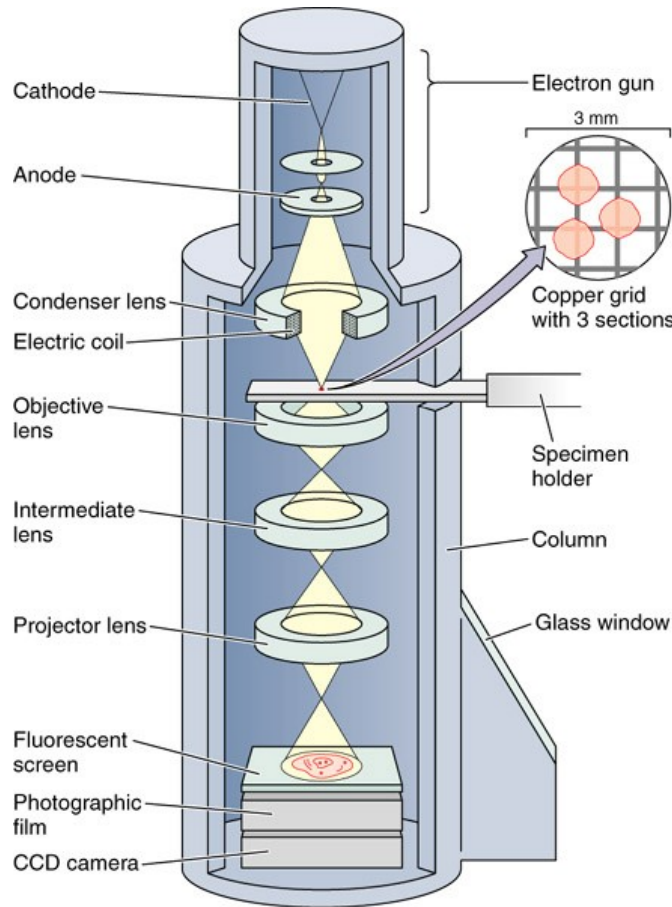
- **Electron microscopes**
- **Transmission electron microscope**
- **Principles of image formation**

# Electron microscopes

Transmission electron microscope

Scanning electron microscope

## Scanning transmission electron microscope

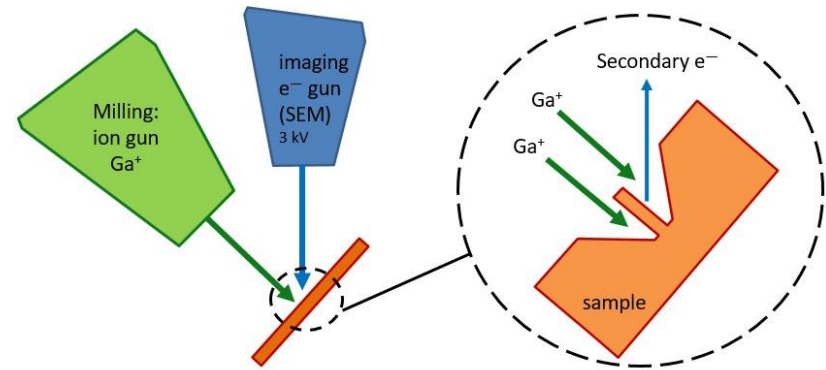
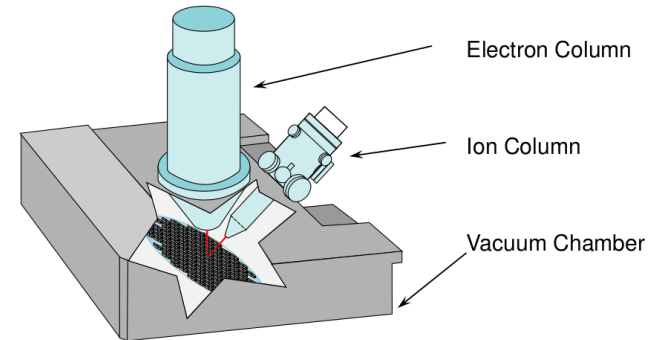
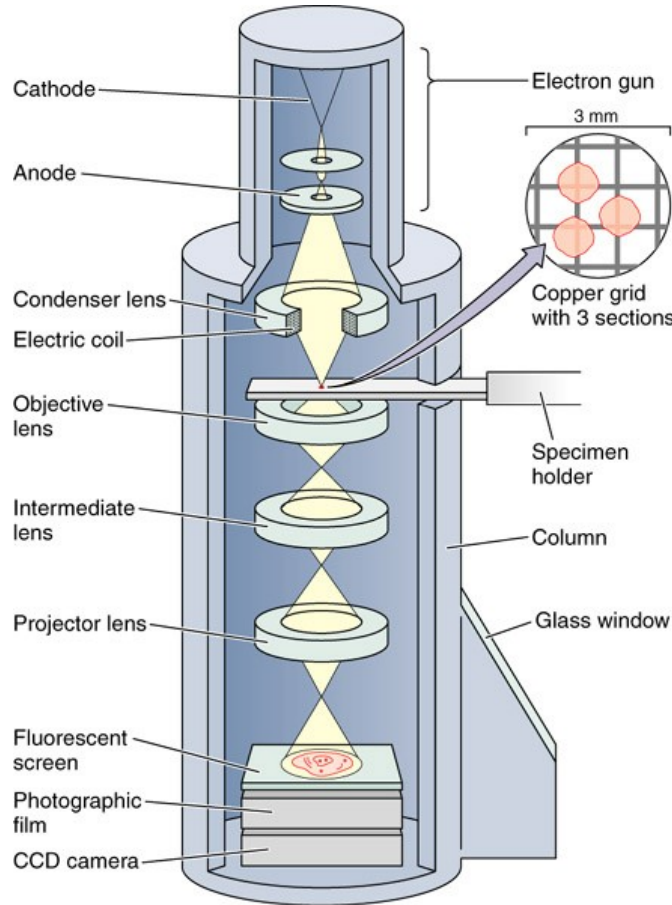


# Electron microscopes

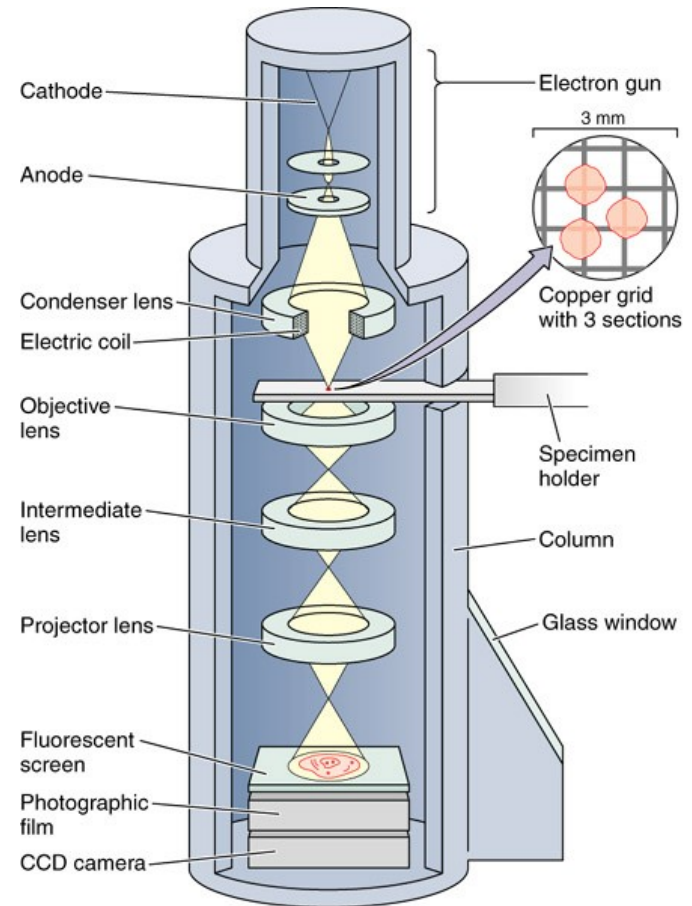
Transmission electron microscope

FIB/SEM microscope

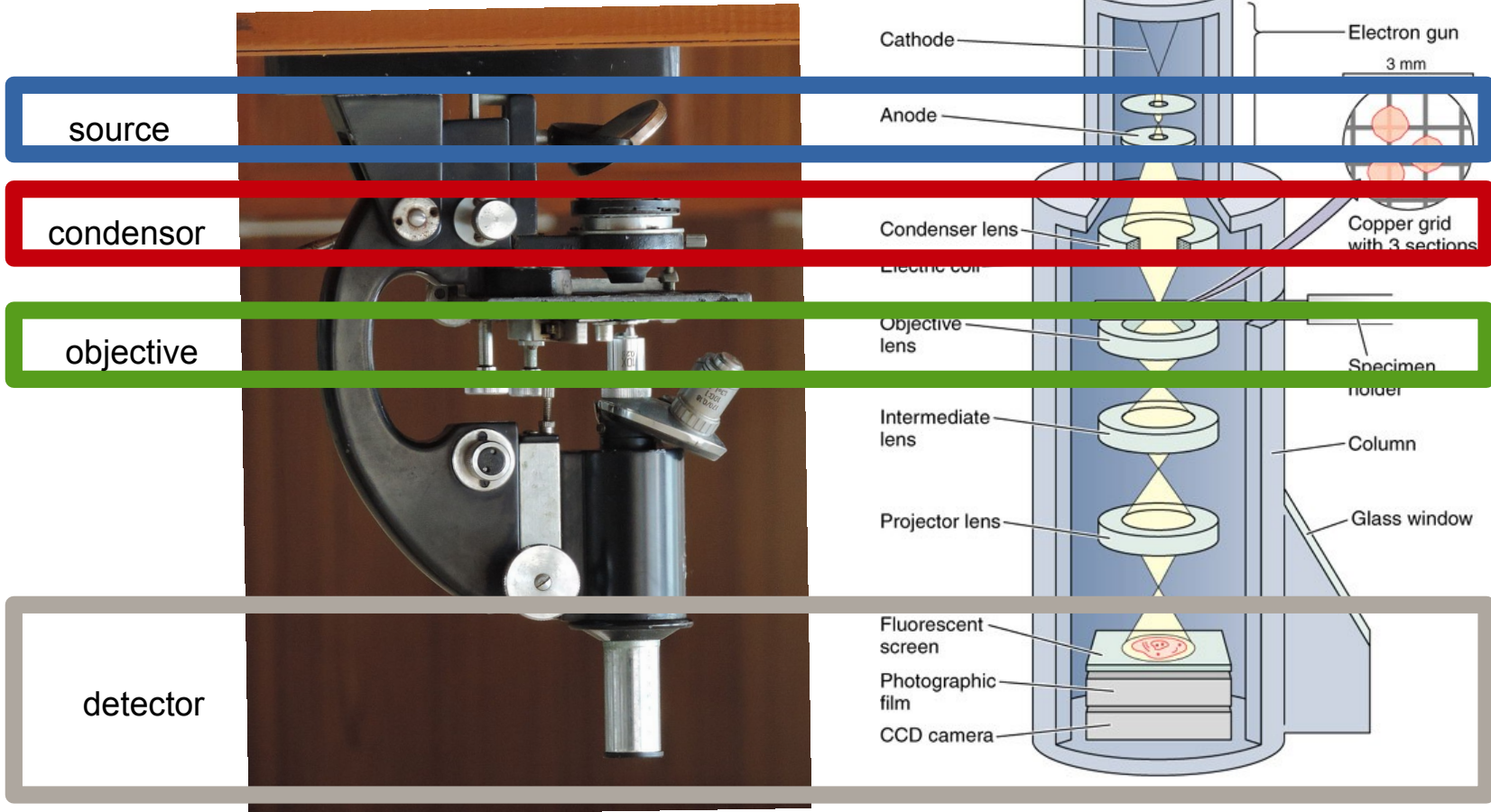
## Scanning transmission electron microscope



# Optical vs. TEM microscope



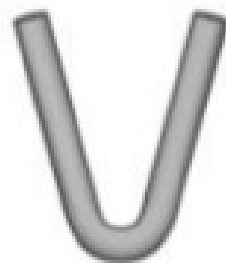
# Optical vs. TEM microscope





# Electron source

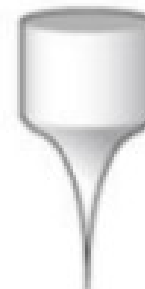
- tungsten filament
- LaB6 crystal
- Field Emission Gun



W filament  
(a)



LaB<sub>6</sub>  
(b)



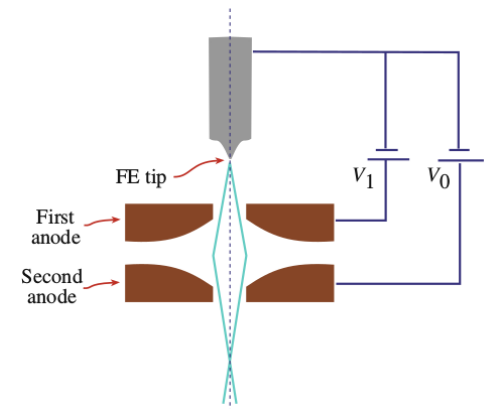
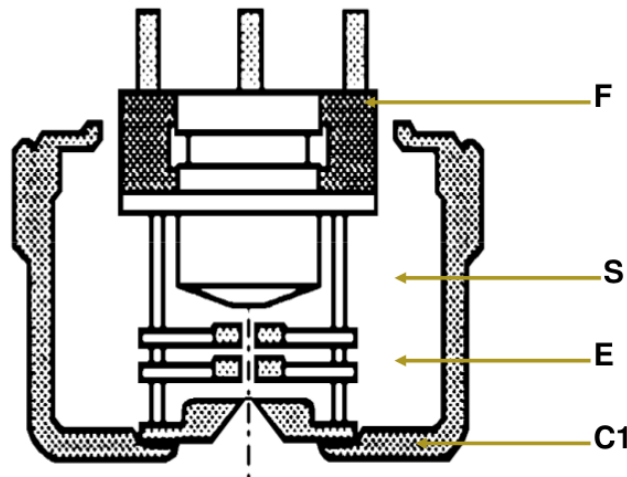
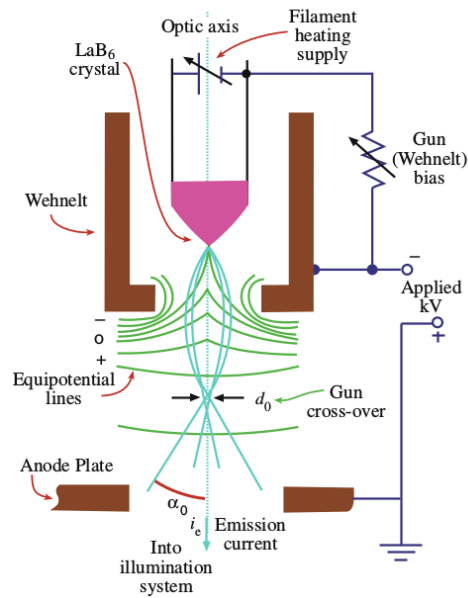
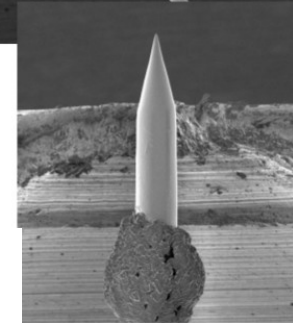
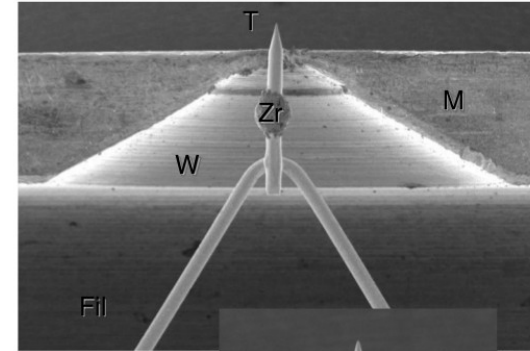
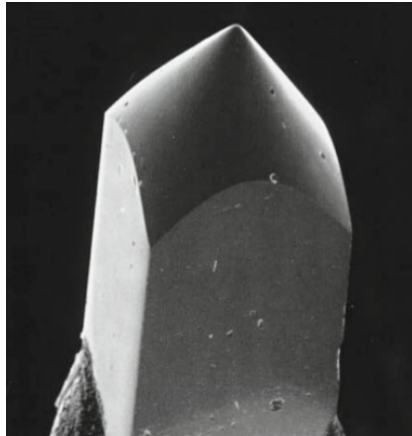
FEG  
(c)

	Units	Tungsten	LaB <sub>6</sub>	Schottky FEG	Cold FEG
Work function, $\Phi$	eV	4.5	2.4	3.0	4.5
Richardson's constant	A/m <sup>2</sup> K <sup>2</sup>	$6 \times 10^9$	$4 \times 10^9$		
Operating temperature	K	2700	1700	1700	300
Current density (at 100 kV)	A/m <sup>2</sup>	5	$10^2$	$10^5$	$10^6$
Crossover size	nm	$> 10^5$	$10^4$	15	3
Brightness (at 100 kV)	A/m <sup>2</sup> sr	$10^{10}$	$5 \times 10^{11}$	$5 \times 10^{12}$	$10^{13}$
Energy spread (at 100 kV)	eV	3	1.5	0.7	0.3
Emission current stability	%/hr	<1	<1	<1	5
Vacuum	Pa	$10^{-2}$	$10^{-4}$	$10^{-6}$	$10^{-9}$
Lifetime	hr	100	1000	>5000	>5000

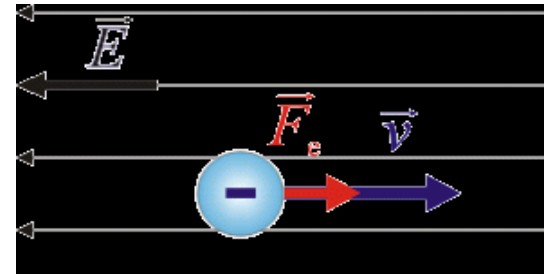
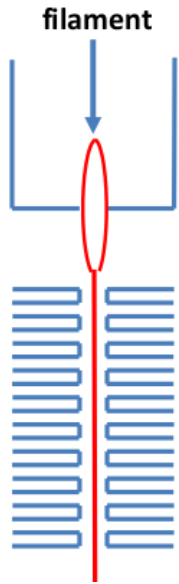
# Electron source

## LaB6

## Field emission gun



# Accelerator

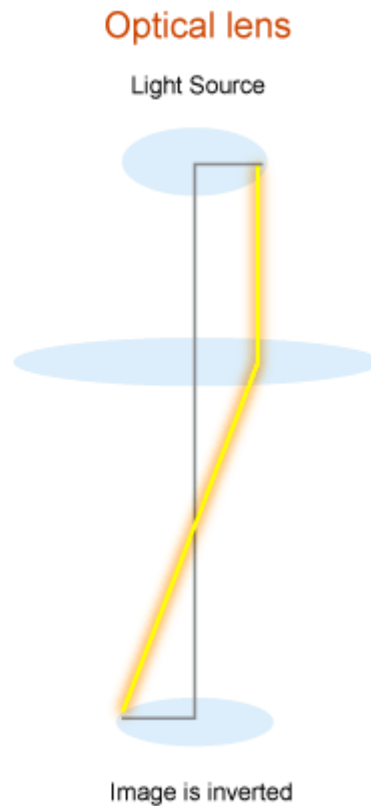
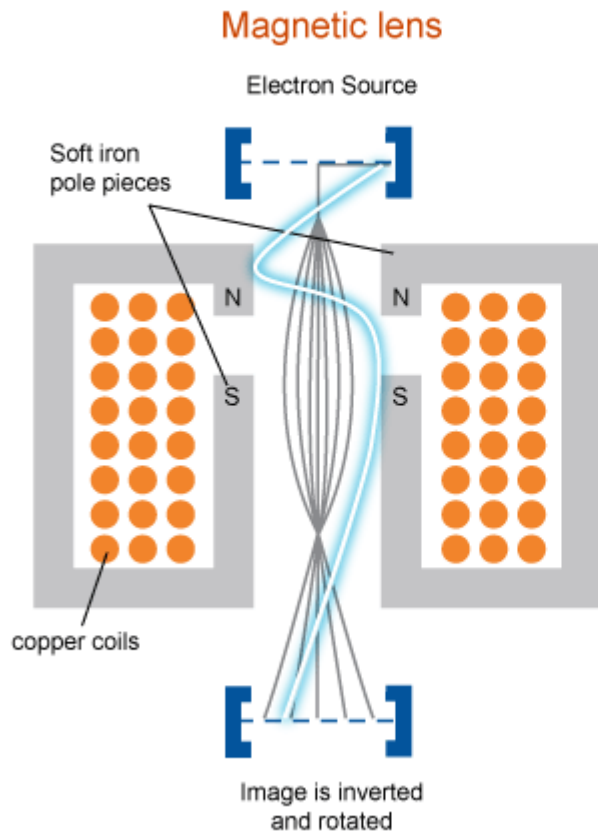


$$\lambda_{\text{de Broglie}} = \frac{h}{p} = \frac{h \cdot c}{\sqrt{(e \cdot V_a)^2 + 2 \cdot e \cdot V_a \cdot m_e \cdot c^2}}$$

Acceleration Voltage [kV]	Non-relativistic wavelength [pm]	Relativistic wavelength [pm]
2	27.35	27.32
20	8.65	8.57
100	3.87	3.69
200	2.73	2.50
300	2.23	1.96

# Electromagnetic lenses

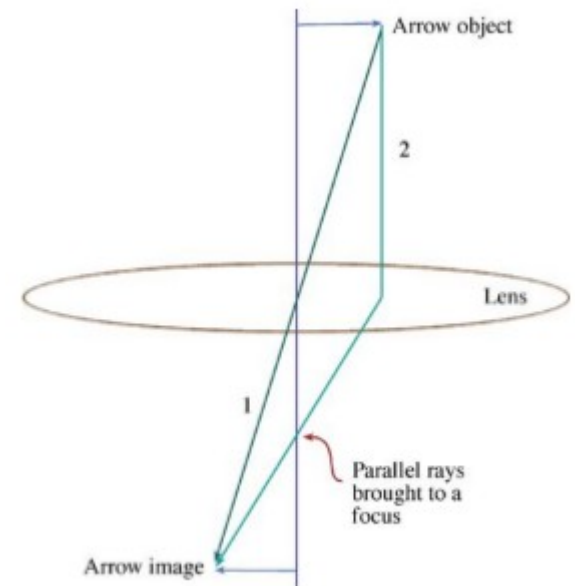
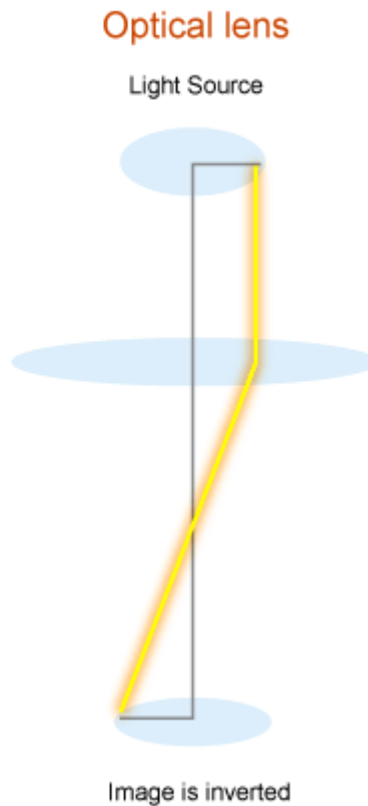
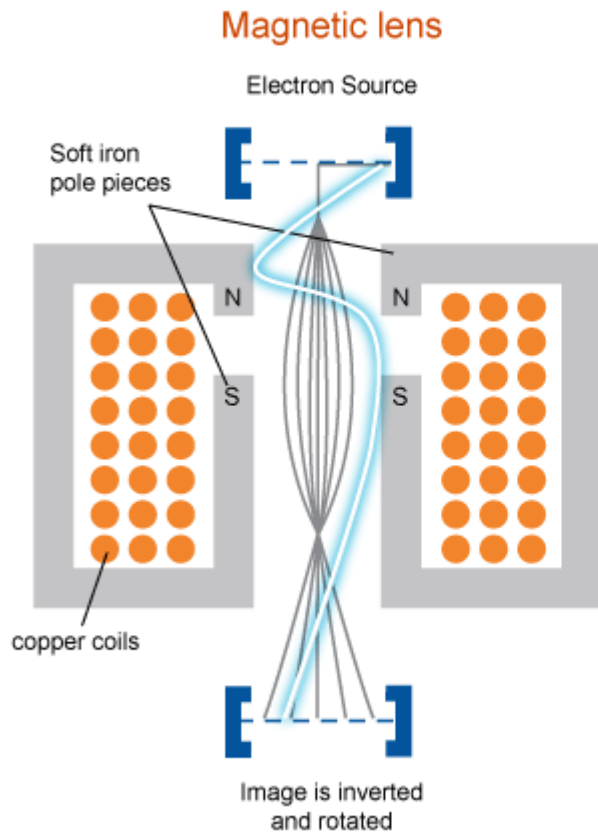
Lorentz force:  $\mathbf{F} = q(\mathbf{E} + \mathbf{v} \times \mathbf{B})$



Magnetic lenses rotate image

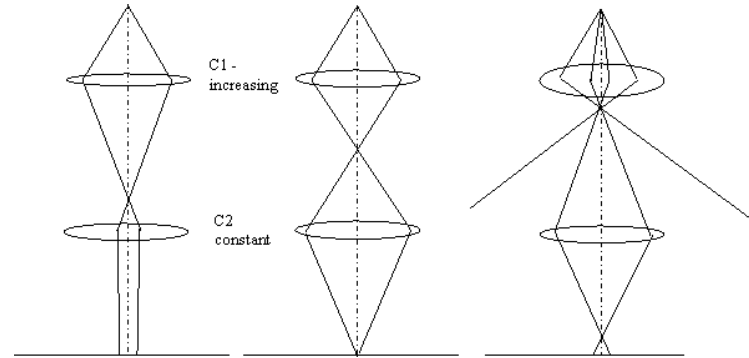
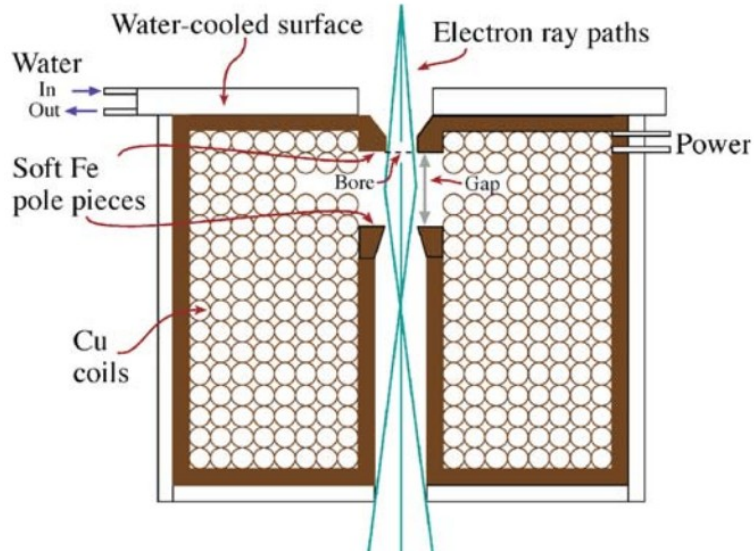
# Electromagnetic lenses

Lorentz force:  $\mathbf{F} = q(\mathbf{E} + \mathbf{v} \times \mathbf{B})$

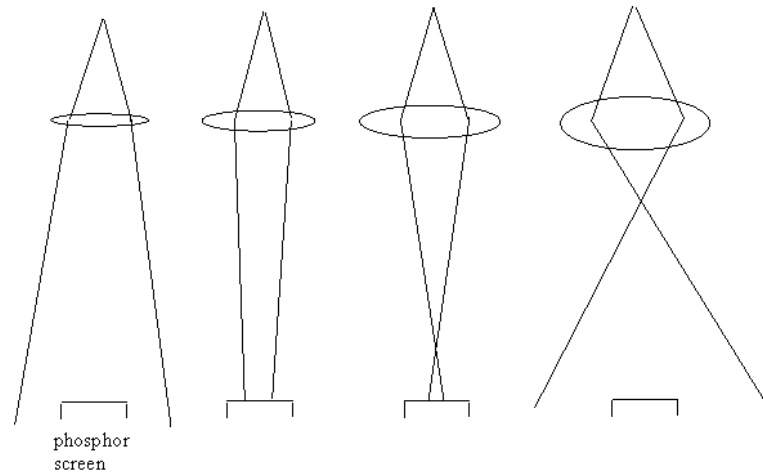


Magnetic lenses rotate image

# Electromagnetic lenses



The distance (power) of the magnetic lens can be changed

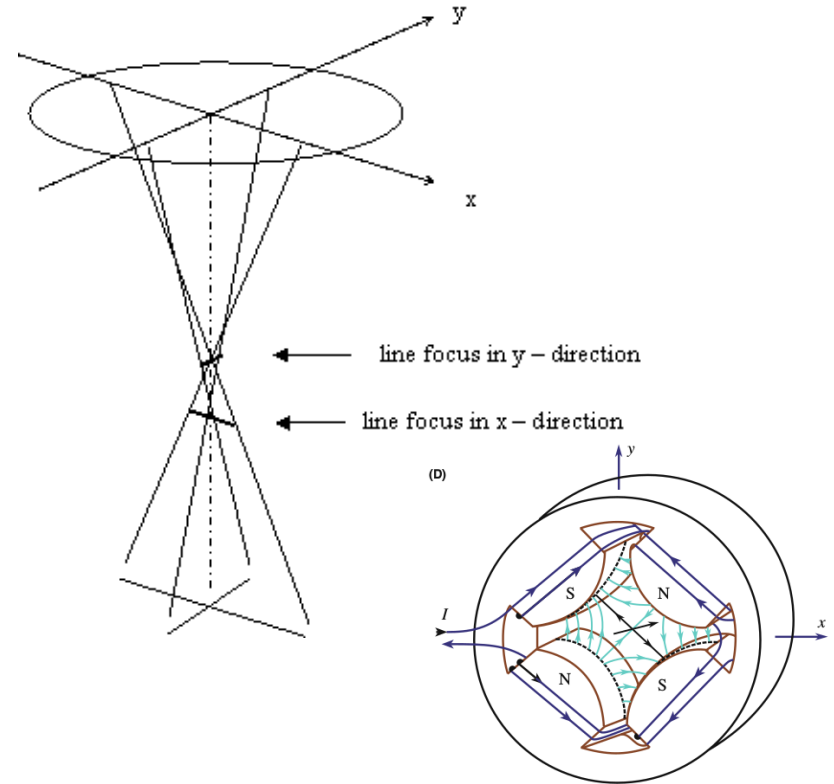
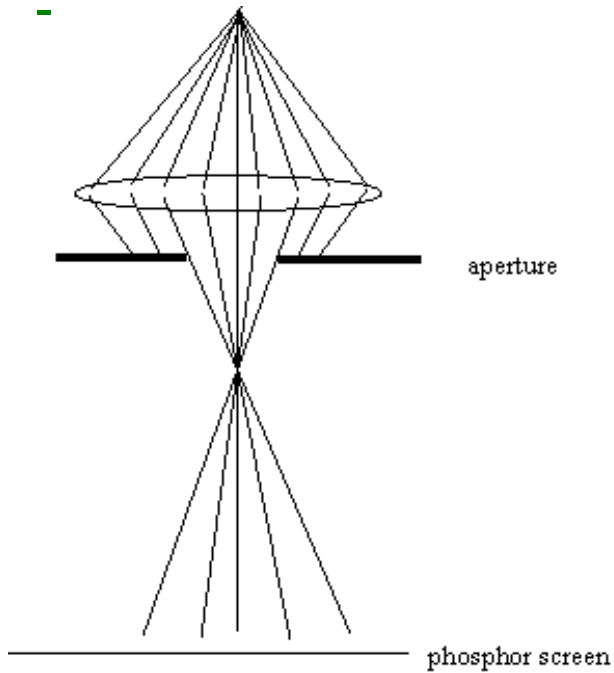


# Electromagnetic lens assembly

## Aperture

## Stigmator

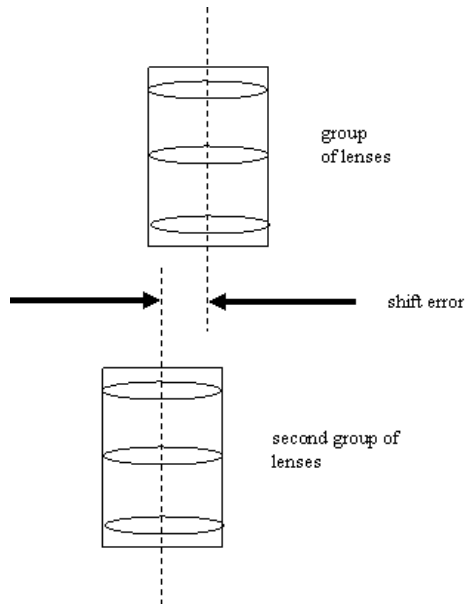
- 
- 



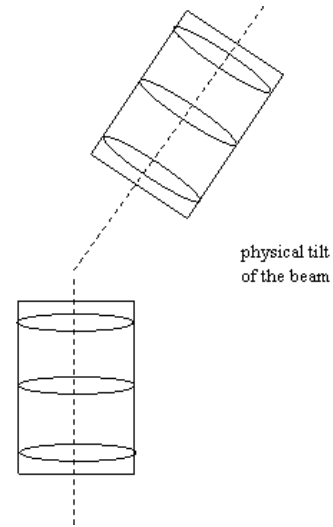
# Multiple lens assemblies

## Shift

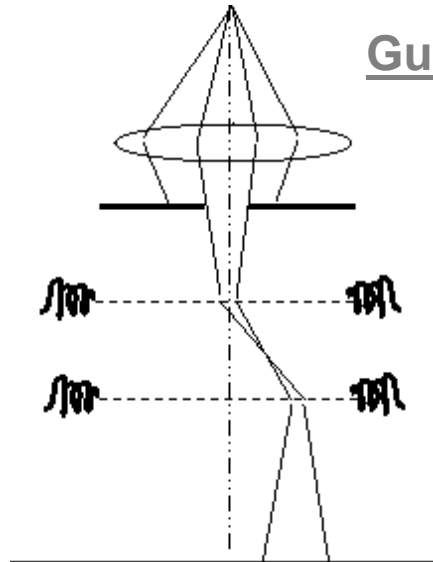
- 
- 



## Tilt



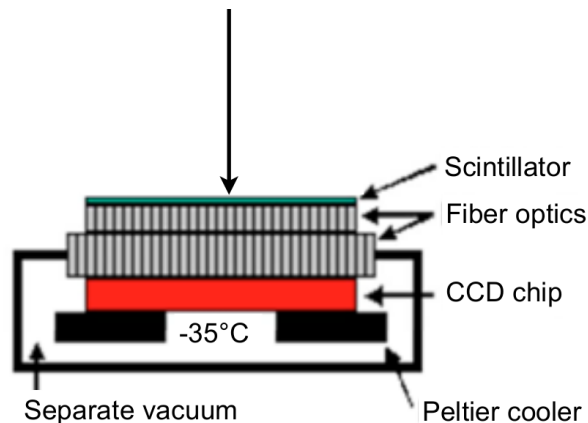
## Gun/beam/image tilt and shift coils



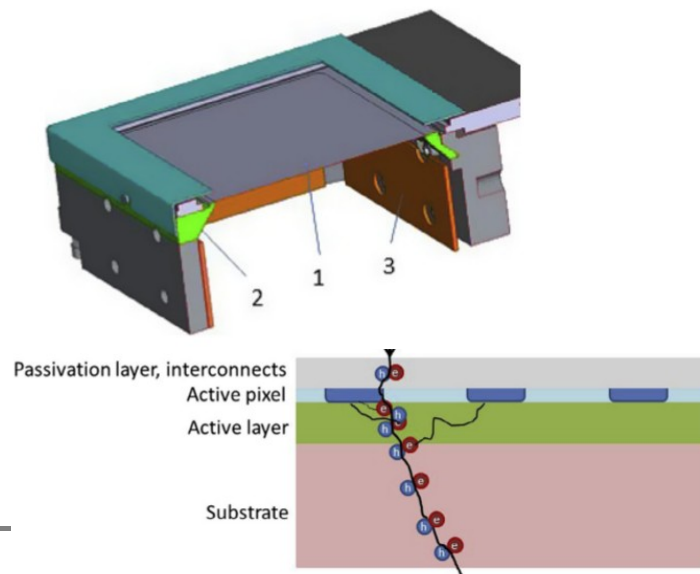


# Detectors

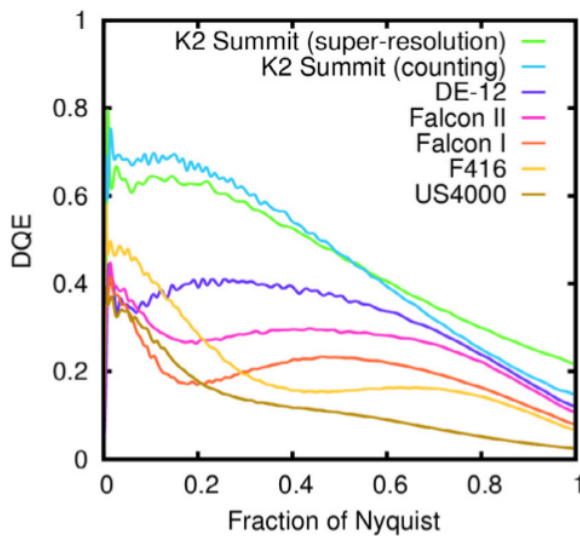
CCD – charge coupled device



CMOS – complementary metal oxide semiconductor



## DQE – detective quantum efficiency

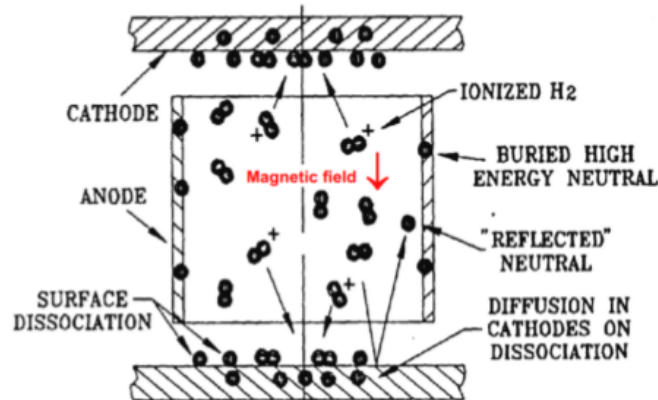
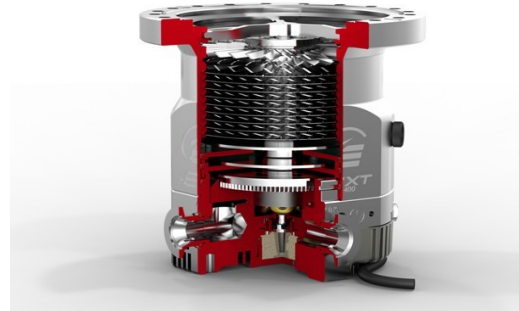
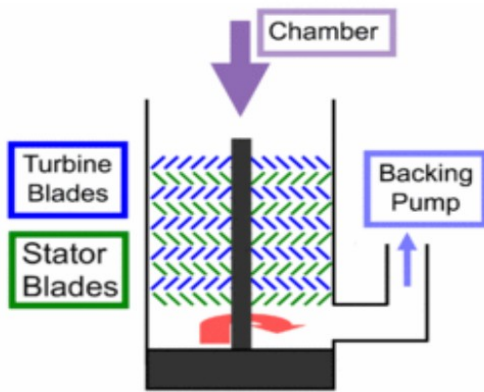
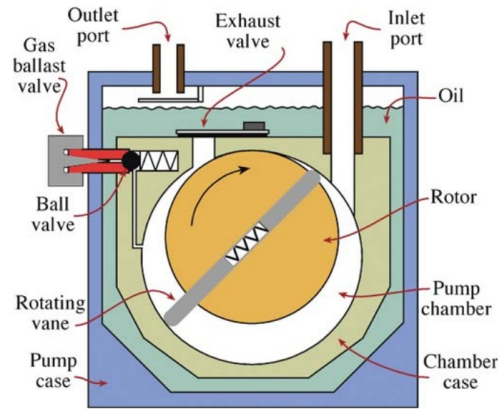


$$DQE(\omega) = \frac{SNR(\omega)_{out}}{SNR(\omega)_{in}}$$

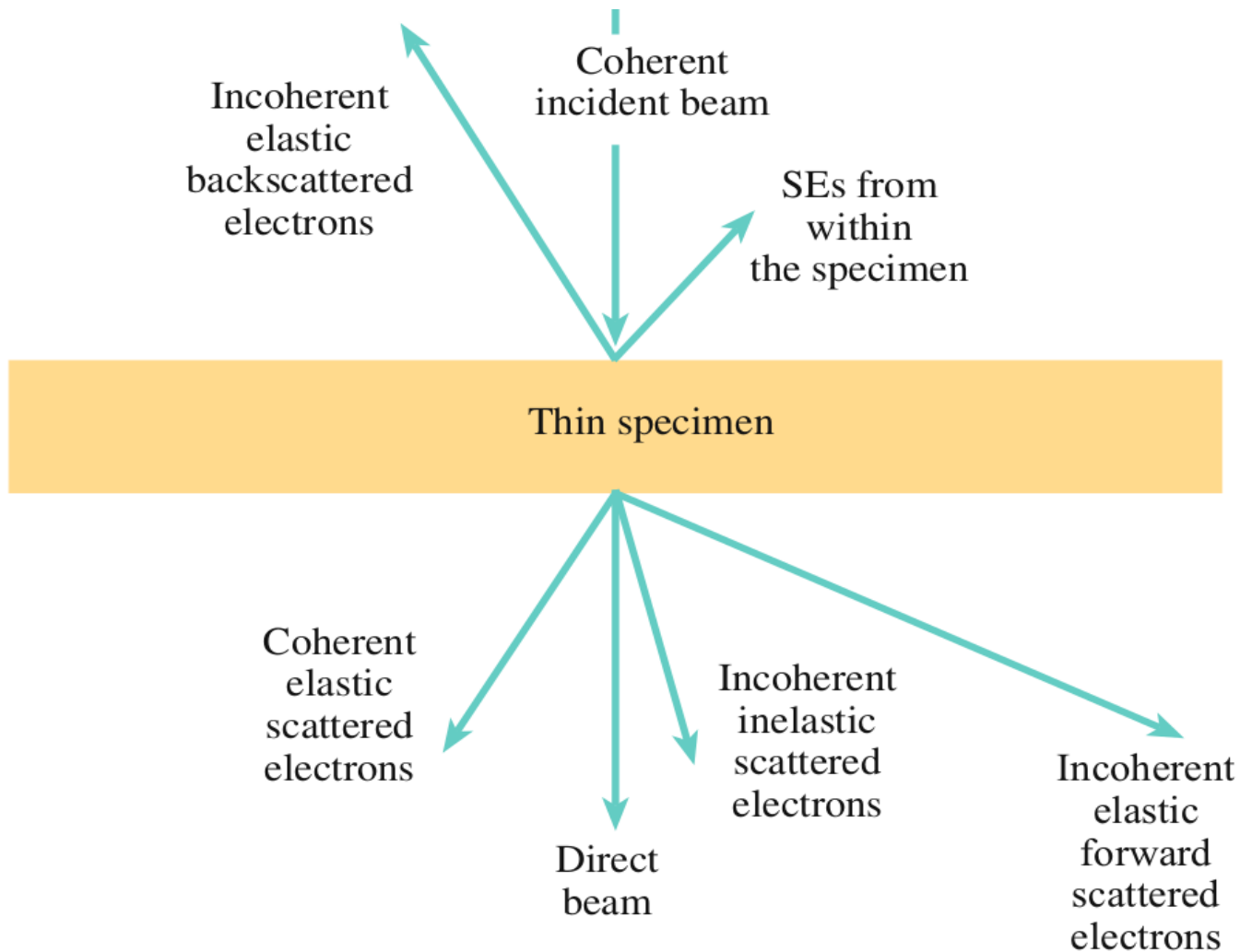
$$DQE(\omega) = \text{sinc}^2(\pi\omega/2)$$

# Vacuum system

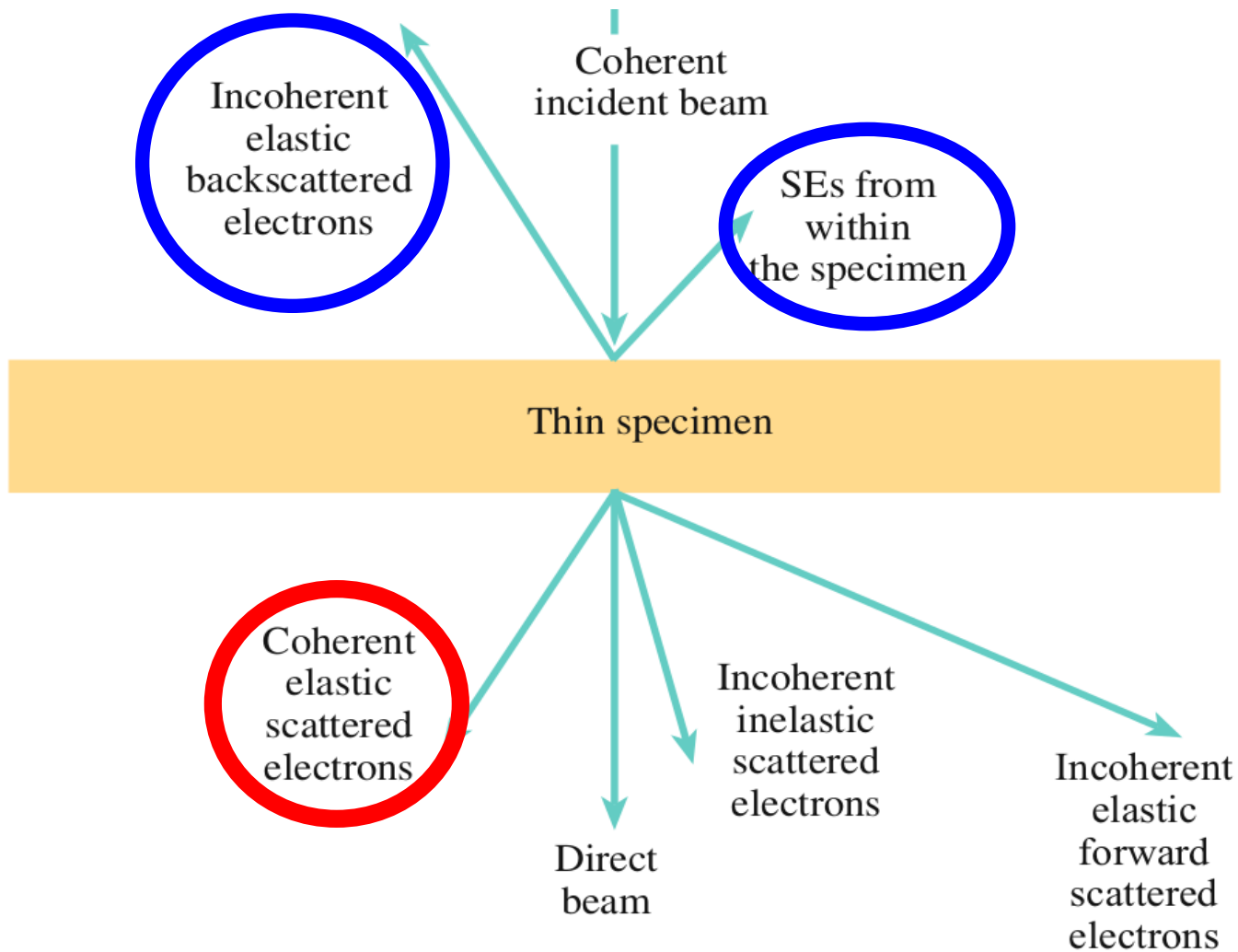
- roughing pump ( $10^5 - 10^{-4}$  Pa)
- turbo molecular pump ( $10^{-2} - 10^{-8}$  Pa)
- ion getter pump ( up to  $10^{-9}$  Pa)



# Interaction of electrons with the specimen

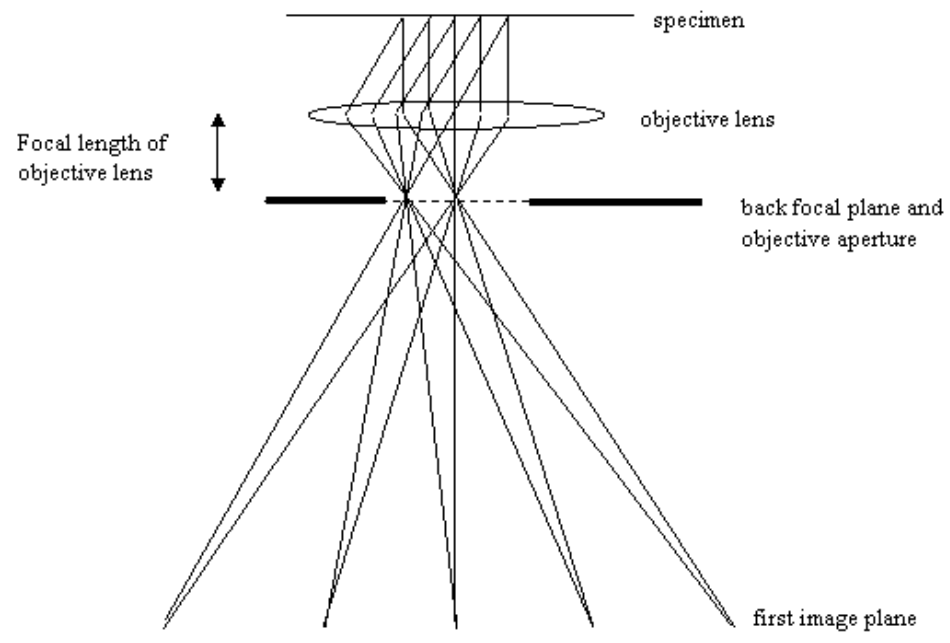
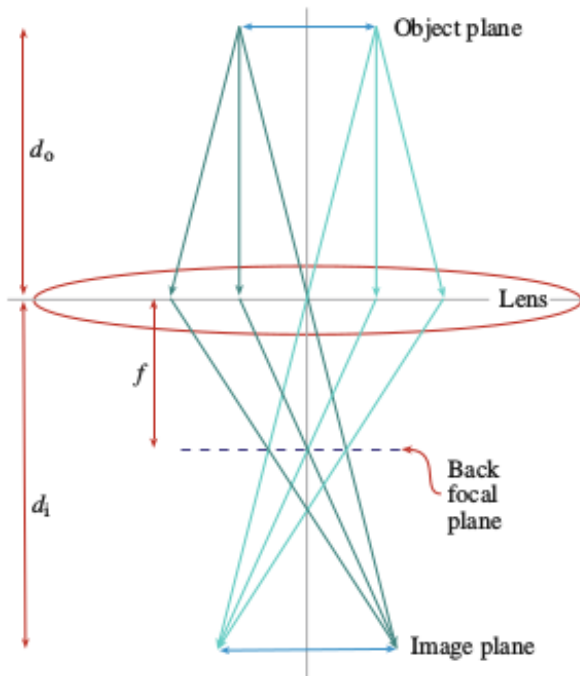


# Interaction of electrons with the specimen



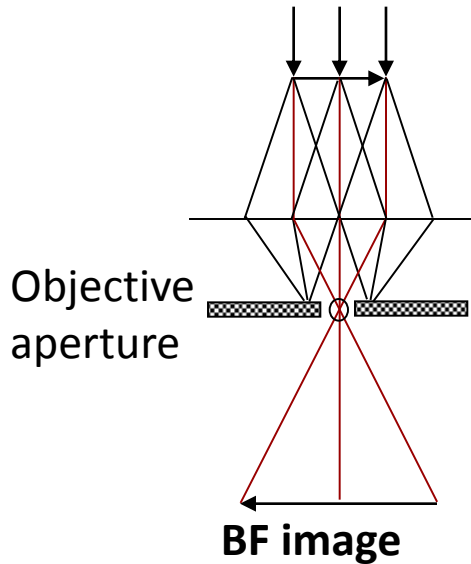
# Transmission electron microscopy

## Image formation



# Transmission electron microscopy

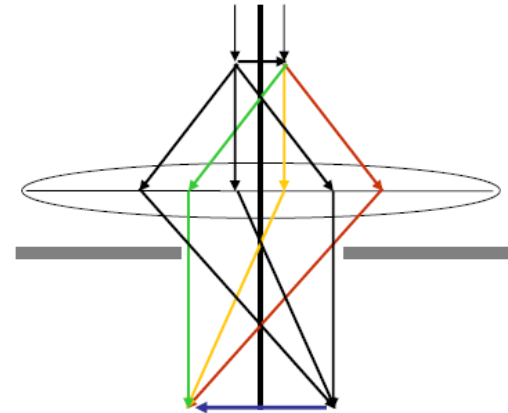
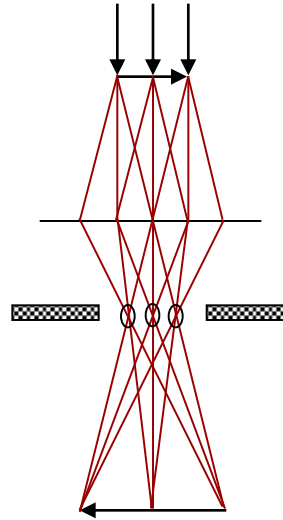
## Amplitude contrast



$$C = \frac{(I_2 - I_1)}{I_1} = \frac{\Delta I}{I_1}$$

- difference in intensity in two adjacent areas

## Phase contrast



- transmitted and diffracted waves travel through different distances

# Thank you for attention

[jiri.novacek@ceitec.muni.cz](mailto:jiri.novacek@ceitec.muni.cz)

